

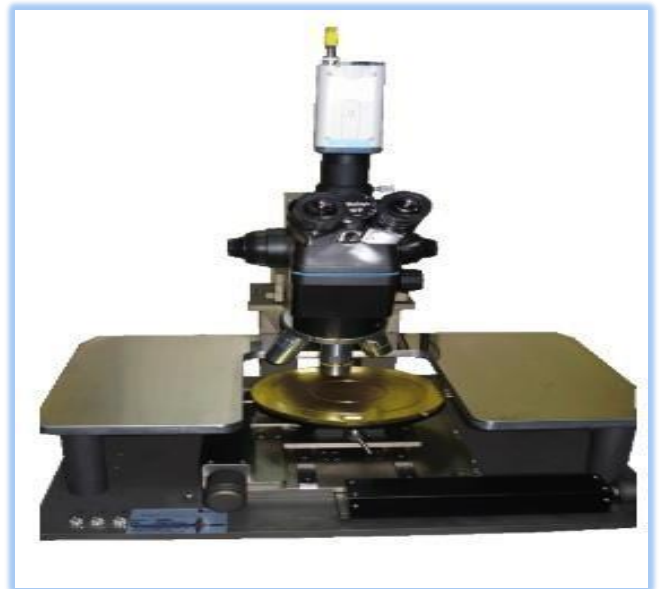
## APS200 | 200 mm Analytical Probe Station for Semiconductor Wafer Testing

### APPLICATIONS:

- IV/CV and RF measurements
- Hall Effect Measurements
- Resistivity Measurements
- Semiconductor Wafer Testing

### FEATURES / BENEFITS

- + Manual stage assembly with up to 210mm x 205mm in X-Y range of motion
- + Powder-coated steel platen holds up to 10 magnetic or vacuum- based positioners.
- + High quality stereo/compound microscopes with high-intensity LED lighting provide outstanding vision at magnifications. Includes camera port
- + Standard boom mount assembly for full-range XYZ positioning of microscope.
- + Bridge mounted scopes is also available on customer's request. XY range of 15mm x15mm (higher range available).
- + Available high resolution Micropositioners
- + RF options available (Up to 67 GHz) include customizable RF probes, RF biasable chuck, and shielding enclosures
- + 4.5" probe card holder



### SPECIFICATIONS

#### Chuck XYZ Stage Travel:

Total travel range	: Up to 210 mm x 205 mm
Travel resolution	: < 1.0 $\mu$ m
Chuck Z axis adjustment	: 10 mm
Chuck Theta travel	: $\pm 5^\circ$ , optional up to $360^\circ$
Chuck Pull Out Stage	: Pull out Stage for easy wafer loading/unloading

## **PLATEN:**

### **Specifications:**

<b>Material</b>	:	<b>Stainless Steel</b>
<b>Chuck to platen height</b>	:	<b>Min. 10 mm</b>
<b>Platen lift control</b>	:	<b>Fixed, Platen lift of up to 25 mm available on request(Optional)</b>
<b>Max. No of Micro-Positioners</b>	:	<b>Up to 10 Micropositioners</b>
<b>Micropositioners Mounting</b>	:	<b>Compatible for both Magnetic as well as Vacuum base micropositioners</b>
<b>RF Micro-Positioner mounting</b>	:	<b>Magnetic/Vacuum base with guided rail</b>
<b>DC Micro-Positioner mounting</b>	:	<b>Magnetic/Vacuum base</b>

## **NON-THERMAL CHUCKS**

### **Standard Wafer Chuck:**

<b>Chuck Connections</b>	:	<b>Coaxial(BNC)/ Triaxial</b>
<b>Chuck Diameter</b>	:	<b>Up to 200 mm</b>
<b>Chuck Material</b>	:	<b>Stainless Steel. Chuck made of other material is available as optional</b>
<b>Chuck surface</b>	:	<b>Planar with centric engraved vacuum grooves</b>
<b>Chuck Sample actuation</b>	:	<b>Vacuum actuation with three zone vacuum holes</b>
<b>Sample Size</b>	:	<b>Min 5mm x 5mm up to 200 mm wafer</b>
<b>Chuck Surface Planarity</b>	:	<b>10<math>\mu</math>m, Optional down to <math>\pm</math>3<math>\mu</math>m</b>

### **RF Wafer Chuck:**

<b>Chuck Connections</b>	:	<b>Coaxial(BNC)/Triaxial</b>
<b>Chuck Diameter</b>	:	<b>Up to 50 mm 2 AUX chuck as optional</b>
<b>Chuck Material</b>	:	<b>Aluminum Plated with Nickel, Copper Plated with Gold</b>
<b>Chuck surface</b>	:	<b>Planar with centric engraved vacuum grooves</b>
<b>Chuck Sample actuation</b>	:	<b>Vacuum actuation with three zone vacuum holes</b>
<b>Sample Size</b>	:	<b>Min 5mm x 5mm up to 200 mm wafer</b>
<b>Chuck Surface Planarity</b>	:	<b>10<math>\mu</math>m, Optional down to <math>\pm</math>3<math>\mu</math>m</b>

### **Auxiliary Chuck:**

<b>Quantity</b>	:	<b>2 Nos of AUX Chuck</b>
<b>Chuck Diameter</b>	:	<b>Up to 50 mm</b>



Chuck Material	:	Derlin, Ceramic, RF absorbing material
Chuck Sample actuation	:	Separate vacuum control switches for auxiliary chucks
Sample Size	:	Min 5mm x 5mm up to 50 mm wafer
Chuck Surface Planarity	:	10 $\mu$ m, Optional down to $\pm$ 3 $\mu$ m

## **ELECTRICAL PERFORMANCE SPECIFICATIONS:**

### Standard Chuck @10 V:

Parameter	Coaxial Chuck	Triaxial Chuck
Maximum voltage between chuck and GND	500 V DC	500 V DC
Isolation	> 2 G $\Omega$	Force to guard > 25T $\Omega$ Guard to shield > 3T Force to shield > 500G $\Omega$
Leakage current	< 50pA	$\leq$ 50fA
Capacitance	< 800pF	< 100fF
Chuck Flatness	$\leq$ 10 $\mu$ m	$\leq$ 10 $\mu$ m

## **THERMAL CHUCK:**

Parameter	Coaxial Chuck	Triaxial Chuck
Temperature Control Method	Resistive type heating	Resistive type heating
Cooling	Water cooling/ Air cooling	Water cooling /Air cooling
Temperature Range	RT - 200 $^{\circ}$ C, Optional up to 600 $^{\circ}$ C	RT - 200 $^{\circ}$ C, Optional up to 600 $^{\circ}$ C
Temperature Control	Linear DC/PID	Linear DC/PID
Temperature Sensor	(RTD) Pt100/ /3DIN, 4-line wired	(RTD) Pt100/ /3DIN, 4-line wired
Temperature Stability	$\pm$ 0.5 $^{\circ}$ C	$\pm$ 0.5 $^{\circ}$ C
Temperature Accuracy	$\pm$ 1 $^{\circ}$ C	$\pm$ 1 $^{\circ}$ C
Connection Interface	RS232	RS232
Chuck Surface Plating	Nickel/Gold	Nickel/Gold
Surface Flatness	$\pm$ 10 $\mu$ m@RT & $\leq$ 30 $\mu$ m@ $\geq$ 300 $^{\circ}$	$\pm$ 10 $\mu$ m@RT & $\leq$ 30 $\mu$ m@ $\geq$ 300 $^{\circ}$ C
Leakage Current	< 100pA	<100fA

## + **Micropositioners:**

<b>Model</b>	<b>Description</b>	
<b>MH100</b>	Fixed Magnet Base	
	Switchable Magnet Base	
	Vacuum Base	
<b>MH100</b>	Foot dimension	<b>70 x 50mm</b>
	Travel range X, Y	<b>12mm</b>
	Travel range Z	<b>12mm</b>
	Feature Resolution	<b>1µm/0.8µm</b>
	TPI resolution	<b>80 TPI/100TPI</b>
<b>MH300</b>	Fixed Magnet Base	
	Switchable Magnet Base	
	Vacuum Base	
<b>MH300</b>	Foot dimension	<b>70 x 35mm</b>
	Travel range X, Y	<b>12mm</b>
	Travel range Z	<b>12mm</b>
	Feature Resolution	<b>3µm</b>
<b>MH500</b>	Switchable magnet base	
	Vacuum Base	
<b>MH500</b>	<b>Foot dimension</b>	<b>80 x 90mm</b>
	<b>Travel range X ,Y</b>	<b>±15 mm</b>
	<b>Travel range Z</b>	<b>±15</b>
	<b>Feature</b>	<b>mm</b>
	<b>Resolution</b>	<b>3µm</b>

## + **Probe Tip Holders with Connecting Cable:**

<b>Model</b>	<b>Description</b>
<b>Coaxial Tip Holder with Coaxial Cable</b>	
<b>SHC15</b>	<b>Spring Holder/1.5m coax cable/BNC male</b>
<b>THC15</b>	<b>Tube Holder/1.5m coax cable/BNC male</b>
<b>NHC15</b>	<b>Nut Holder/1.5m coax cable/BNC male</b>
<b>Triaxial Tip Holder with Triaxial Cable</b>	
<b>THT15</b>	<b>Tube Holder/1.5m Triax cable/Triax male</b>
<b>NHT15</b>	<b>Nut Holder/1.5m Triax cable/Triax male</b>
<b>High Frequency Probe Arms</b>	
<b>MWA-EW</b>	<b>HF probe arm (east-west)</b>
<b>MWA-NS</b>	<b>HF probe arm(north - south)</b>

**System Dimensions:** 660mm wide x660mm deep x 700mm high

**Weight:** 80kg to 150kg depending on options selected